

## Call for Papers - DPS 2023

# 44<sup>th</sup> International Symposium on Dry Process

November 21(Tue) - 22(Wed), 2023 Winc Aichi, Nagoya, Japan

#### Paper Submission Deadline: July 21, 2023 Author instructions and information about DPS can be found at: http://www.dry-process.org/2023/





The **44th** International Symposium on Dry Process (DPS2023) will be held at Winc Aichi, Nagoya, Japan, from November 21 to 22, 2023. The Symposium covers all aspects of the rapidly evolving fields of dry processes, including but not limited to plasma etching and deposition processes, diagnostics and modeling of plasmas and surfaces, and surface modifications by plasmas, for the

applications in, e.g., microelectronics, power devices, sensors, environmental protection, biological systems, and medicine. The DPS has provided valuable forums for in-depth discussion among professionals and students working in this exciting field for more than three decades.

#### Theme:

Dry processes and related technologies from fundamentals to applications

- Topics:
- 1. Etching Technologies
  - 2. Manufacturing Technologies (AEC, APC, EES, FDC)
  - 3. Surface Reaction and Damage
  - 4. Plasma Diagnostics and Monitoring Systems
  - 5. Computational Approaches (Modeling, Simulation, Machine Learning, Al, Informatics, DX) for Dry Process
  - 6. Plasma Generation (Equipment/Source)
- 7. Deposition Technologies (CVD / PVD)
- 8. Atomic Layer Processes (ALD/ALE)
- 9. Dry process for Green Transformation:GX (Energy saving technology, Alternative gas, 3D-IC/Packaging)
- 10. Plasma Processes for New Material Devices (MRAM, Power, Organic, III-V, 2D)
- 11. Plasma Processes for Biological and Medical application, MEMS
- 12. Atmospheric Pressure Plasma and Liquid Plasma
- **13. New Dry Process Concepts**

#### Arranged session:

- AS1 Challenges to overcome the limits for high aspect ratio etching
- AS2 Atomic layer processes (ALE/ALD/ASD) toward 2nm and beyond
- AS3 How AI and Machine Learning are transforming dry process technologies

For further general information, please contact: e-mail:dps2023@officepolaris.co.jp

Organizing Committee Chair: Miyako Matsui (Hitachi, Ltd.) Executive Committee Chair: Daisuke Ogawa (Chubu University) Program Committee Chair: Tomihito Ohba (Lam Research Corp.) Publication Committee Chair: Kazunori Koga (Kyushu University)

### URL: http://www.dry-process.org/2023/